

Notice of References Cited	Application/Control No. 10/561,758		Applicant(s)/Patent Under Reexamination SNEH, OFER	
	Examiner Bret Chen		Art Unit 1792	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-5,871,805	02-1999	Lemelson, Jerome	427/8
*	B	US-6,096,371	08-2000	Haaland et al.	427/10
*	C	US-4,612,206	09-1986	Shimozato et al.	427/9
*	D	US-7,537,018	05-2009	Curran et al.	137/3
*	E	US-2003/0068534	04-2003	Ohkawa et al.	428/701
*	F	US-2004/0126485	07-2004	Thompson et al.	427/126.5
*	G	US-2007/0231460	10-2007	Ukigaya, Nobutaka	427/8
*	H	US-2007/0026134	02-2007	Shirley et al.	427/009
*	I	US-6,409,837	06-2002	Hillman, Joseph T.	118/712
*	J	US-5,153,072	10-1992	Ratner et al.	428/461
*	K	US-2002/0172768	11-2002	Endo et al.	427/255.28
*	L	US-6,342,277	01-2002	Sherman, Arthur	427/562
*	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Khanna, R.K., et al., "Thin-Film Infrared Spectroscopic Method for Low-Temperature Vapor Pressure Measurements". J. Phys. Chem. 1990, 94, pp.440-442.			
	V				
	W				
	X				

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.